

In-situ observation of phase transformation during ion beam irradiation

Jonghan Won¹, James A. Valdez²

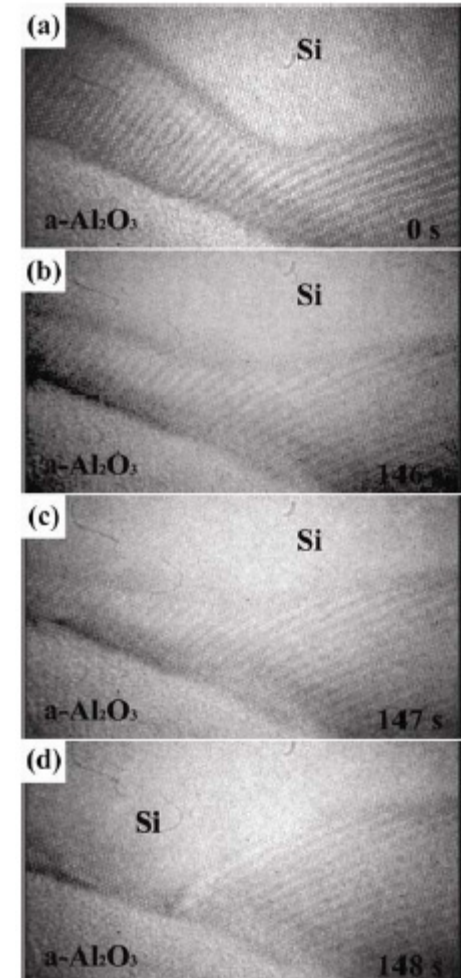
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²MST-8, Los Alamos National Laboratory, USA



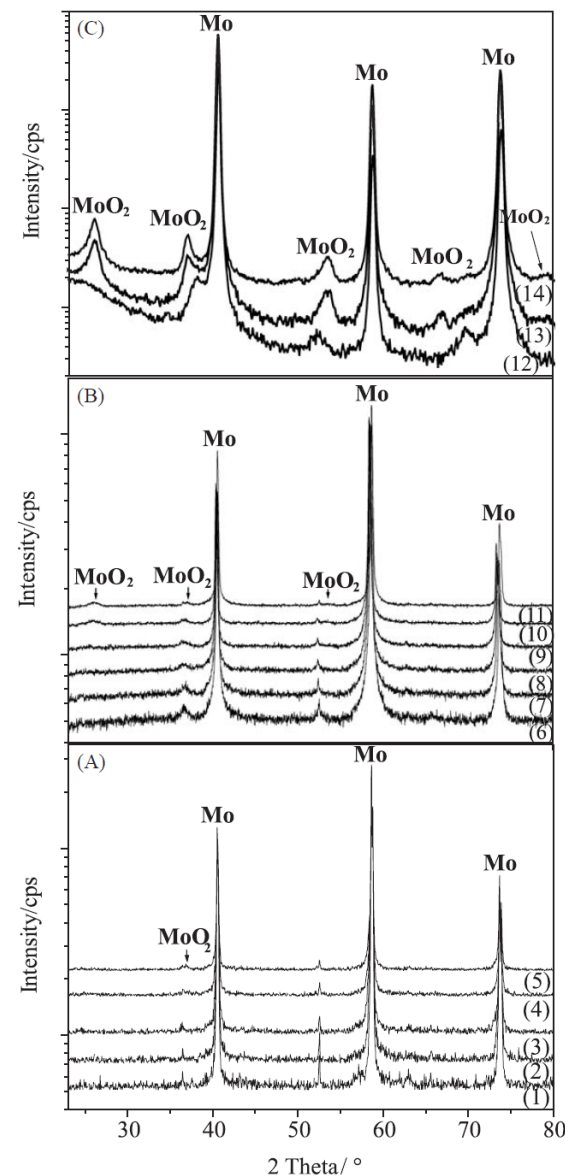
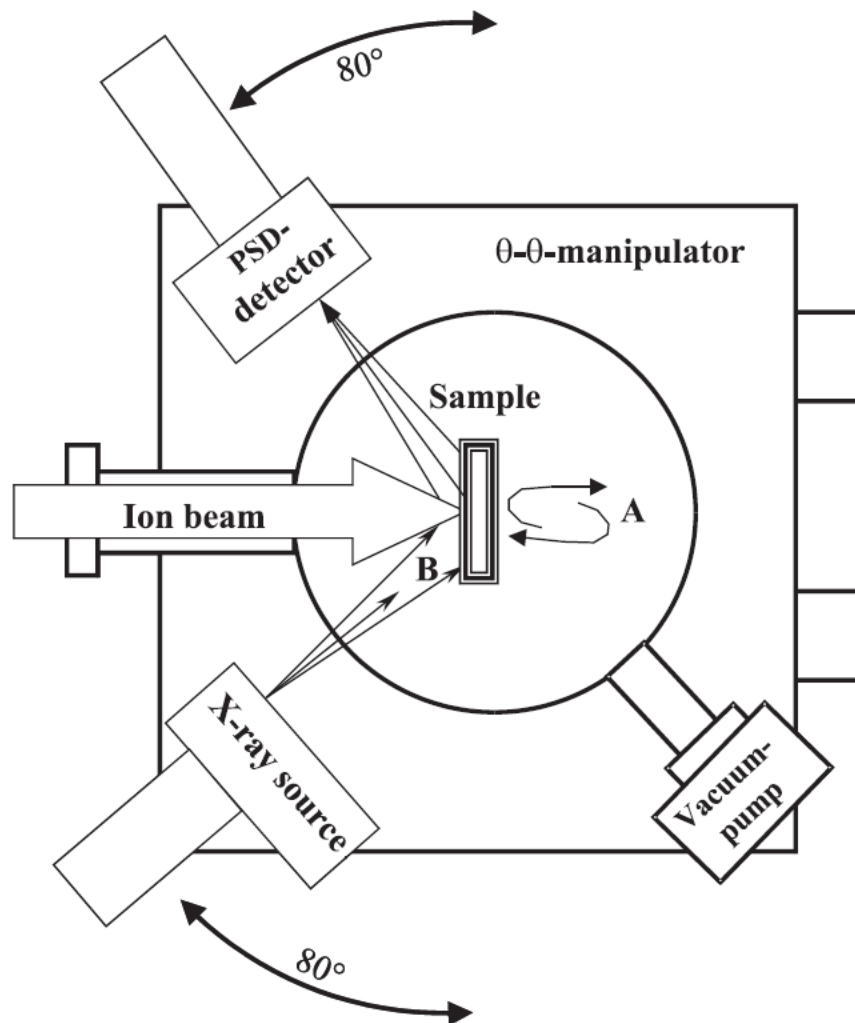
➤ What is In-situ observation ?

1. Real-time data acquisition
 - providing a “live” image or graph
2. Keeping the exact same position during observation
3. Saving time and effort



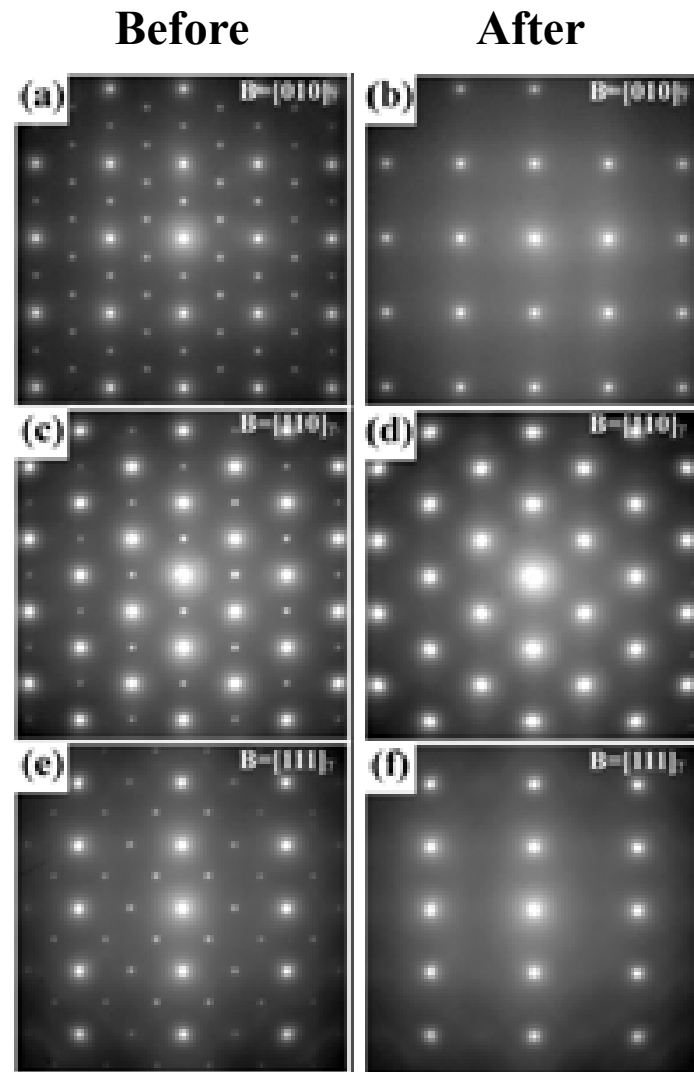
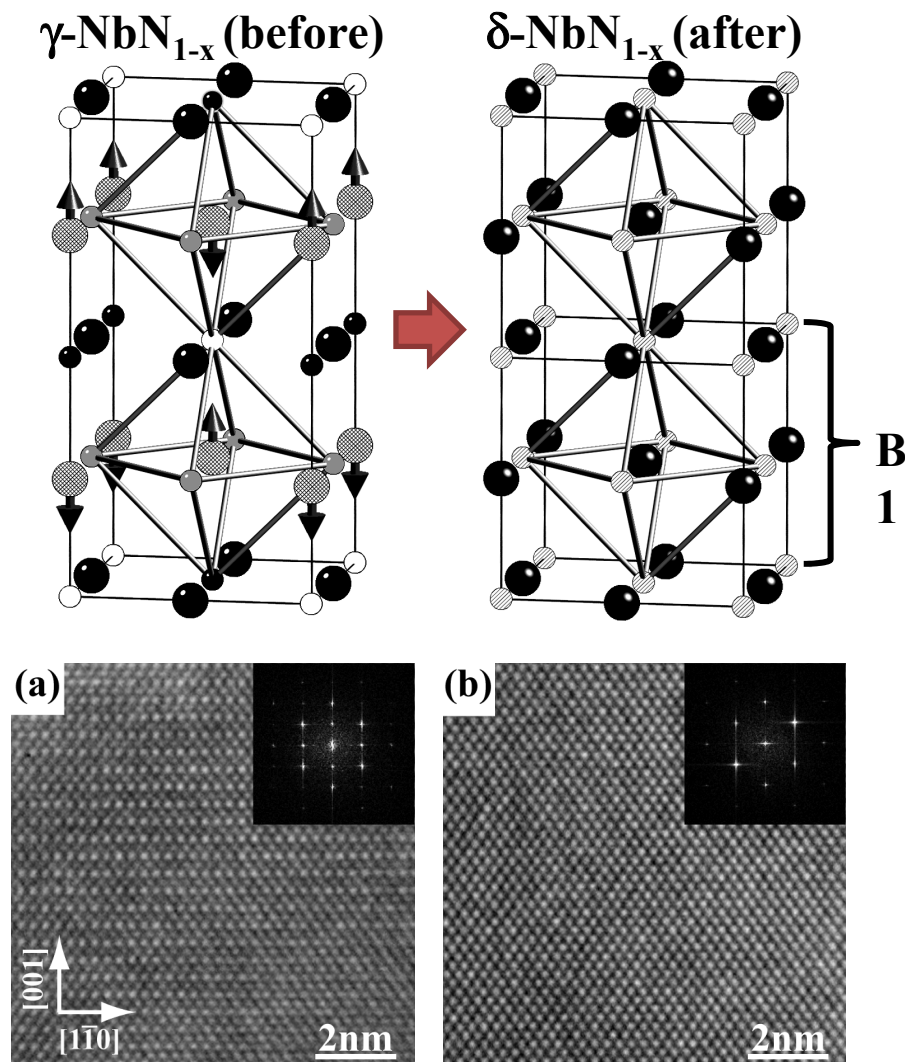
* J.Won, Doctoral dissertation

In-situ observation during ion beam irradiation (XRD)



* Y. Bohne et al. Vacuum 76 (2004)

In-situ TEM observation during e⁻ beam irradiation



*J.Won et al., Scripta Materialia 60 (2009)

Reflection high-energy electron diffraction (RHEED)

- A high-energy electron beam (3-100 keV) is directed at the sample surface at a grazing angle of incidence
- It is possible to use both kinematic (elastic) and dynamic (inelastic) scattering

Advantages

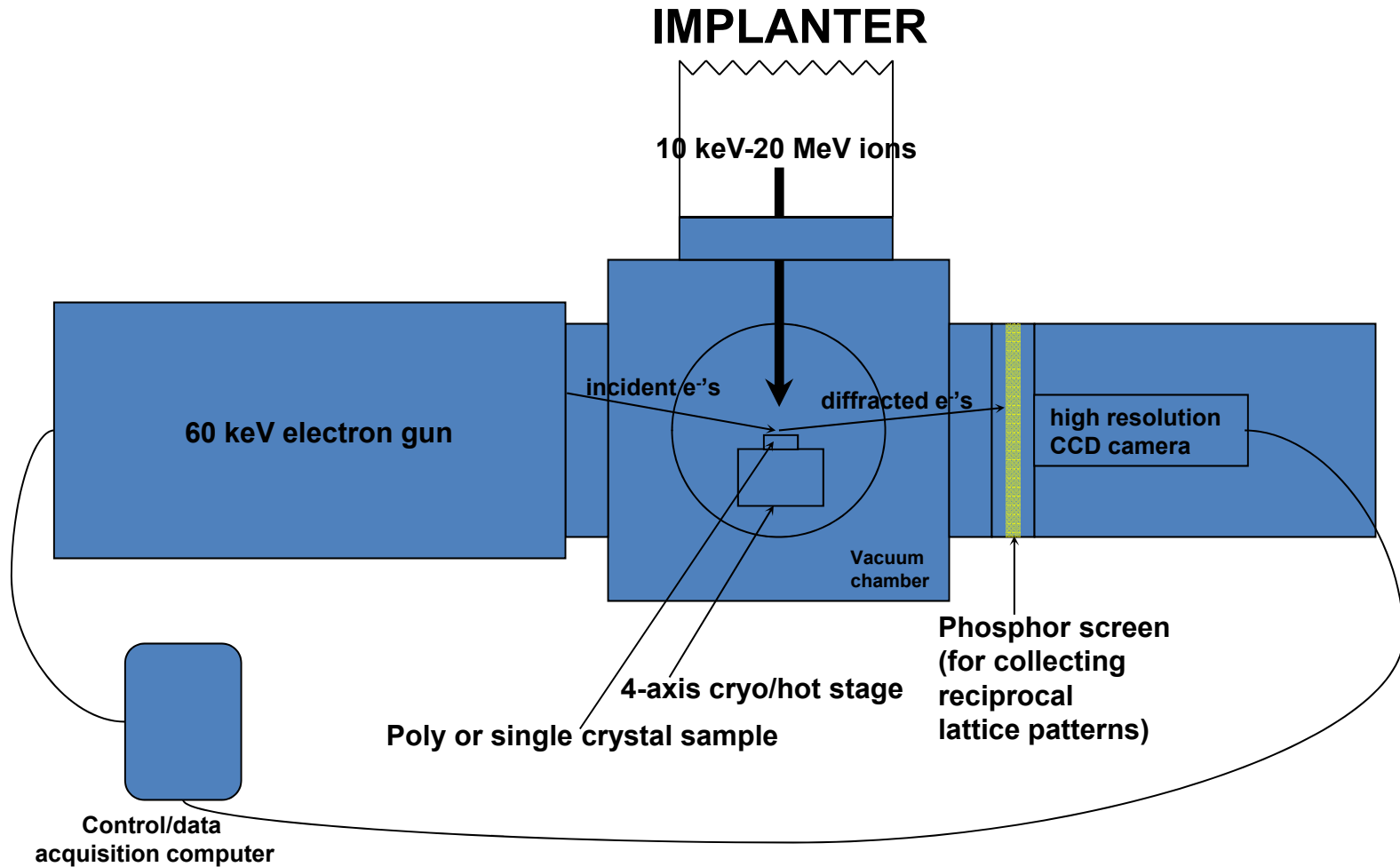
- ▶ High surface sensitivity
 - ability to measure very few atomic layers beneath the surface
- ▶ In-situ observation
 - phosphor screen with charge-coupled device (CCD) camera
 - real time sequential images and movie can be generated

	XRD	TEM	RHEED
Observation area	large	very small	large
Observation depth	deep	>100 nm	better than TEM
Instrument cost	high	high	Low
nondestructive	yes	no	yes

Experimental procedure

- ▶ **Specimen** : LaAlO_3 single crystal (MTI corporation)
 - Rhombohedral at 25 °C and Cubic at > 435 °C, (100) surface normal
- ▶ **Ion implanter**: 200 kV Varian Implanter, 100 keV Ar^{++} source
- ▶ **RHEED**: Guns system from STAIB Instruments (up to 60 keV)
Imaging system (kSA 400 analytical RHEED system)
from k-Space associates, Inc.
- ▶ **Characterization**
 - GIXRD: Bruker AXS D8 Advance X-ray diffractometer
(Cu-K_α and θ - 2θ geometry)
 - TEM : Sampling-combination of mechanical grinding and ion milling (PIPS)
Observation- FEI Technai F30 TEM/STEM

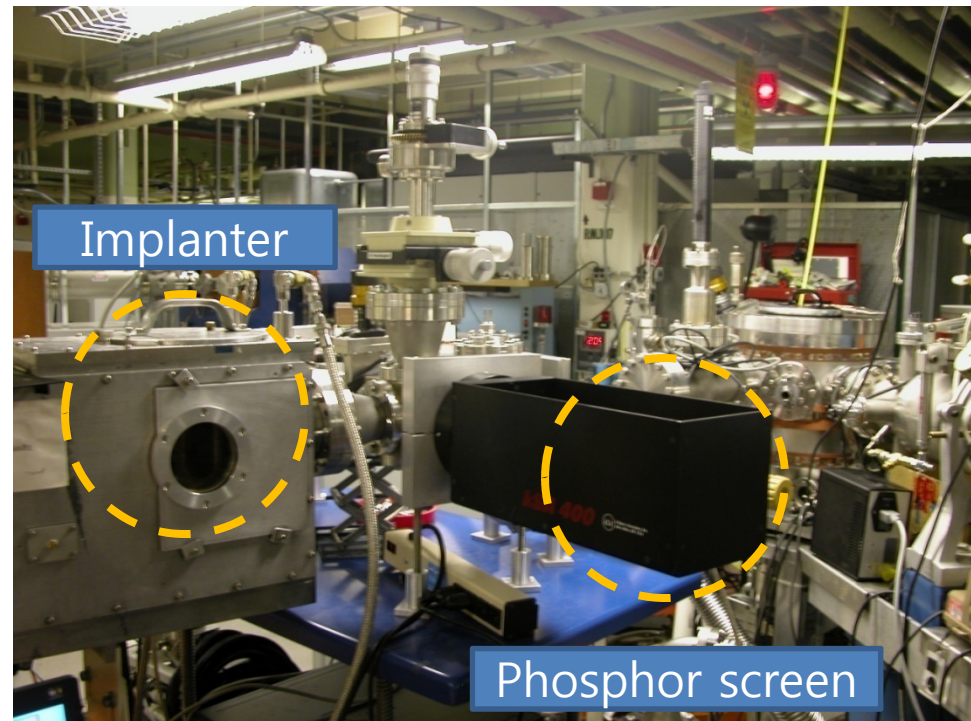
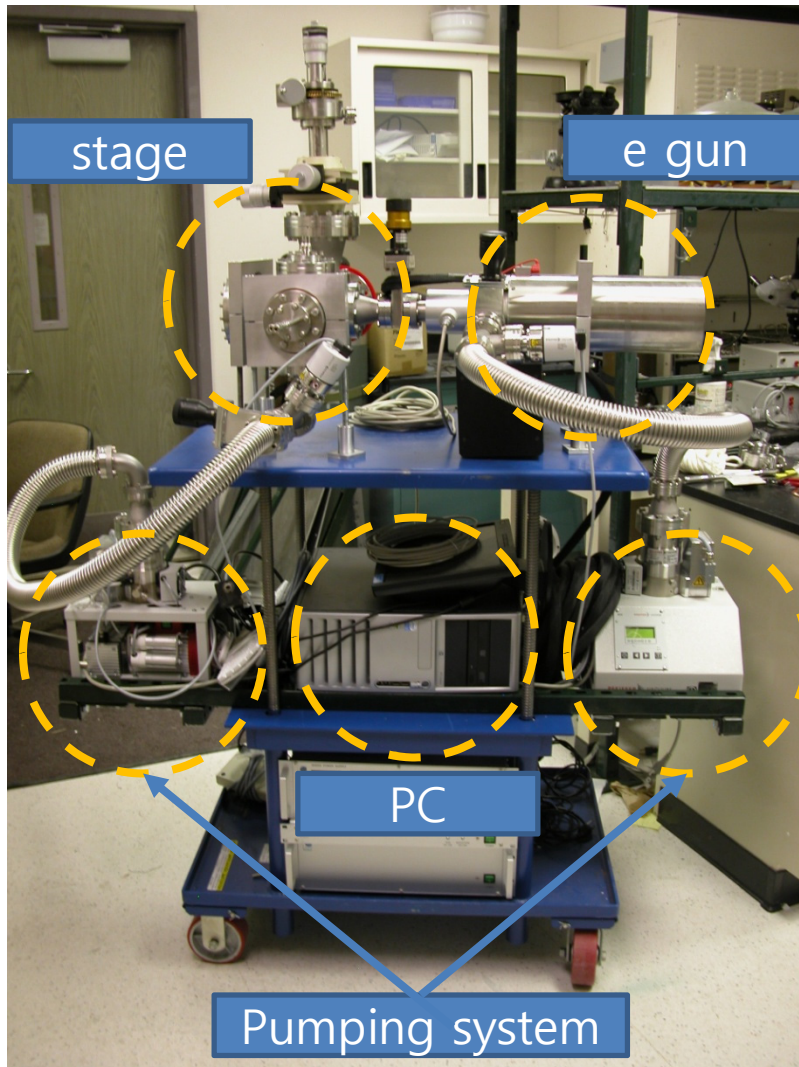
System configuration



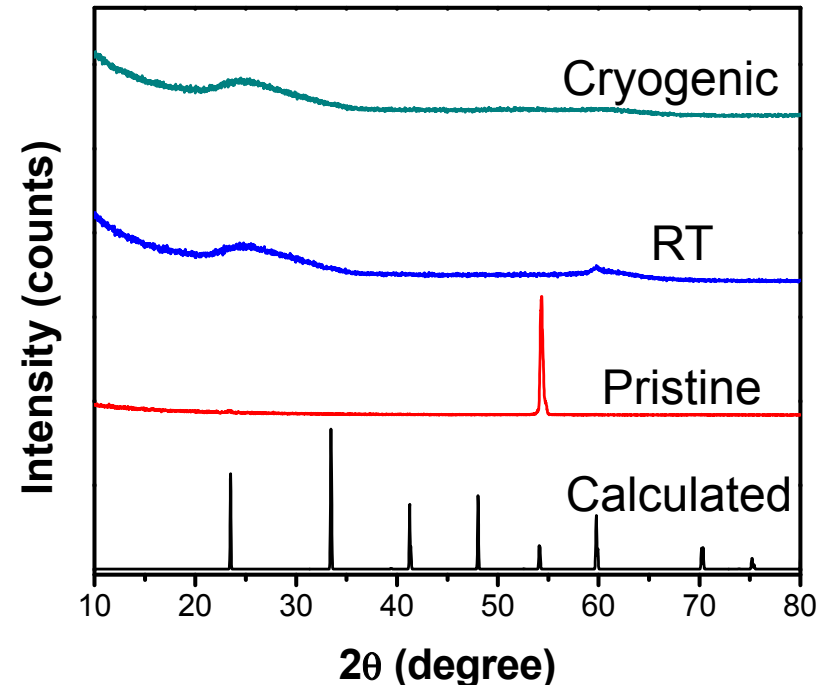
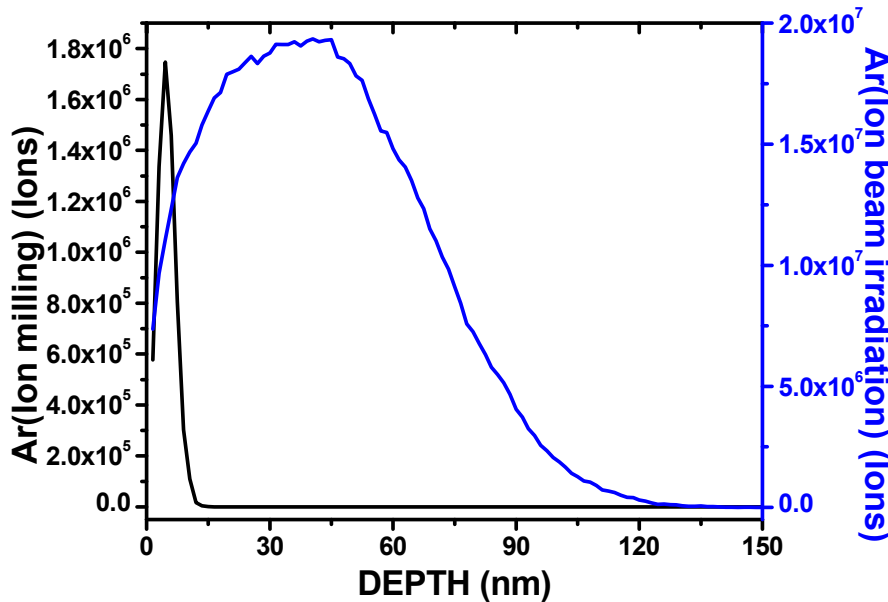
System configuration

1. on implanter
2. RHEED

- electron gun
- sample stage
- phosphor screen and CCD camera
- control/data acquisition PC

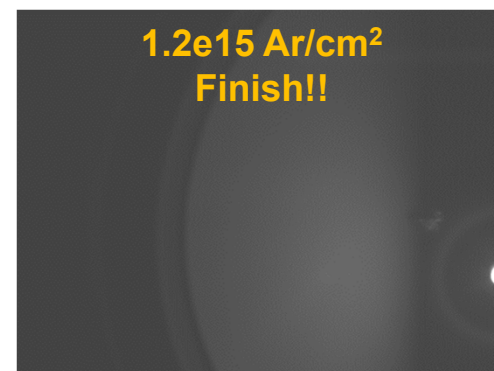
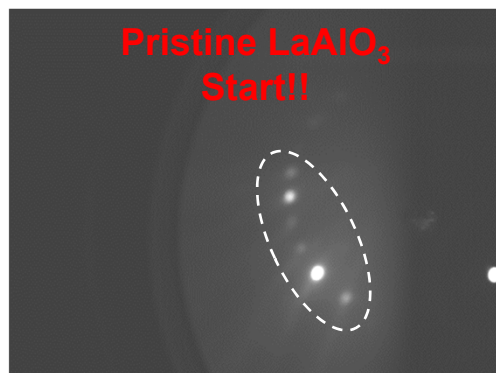


Ion penetration depth calculated by SRIM2009 and GIXRD patterns from LaAlO_3

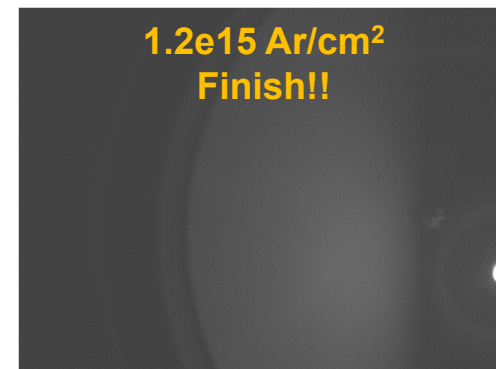
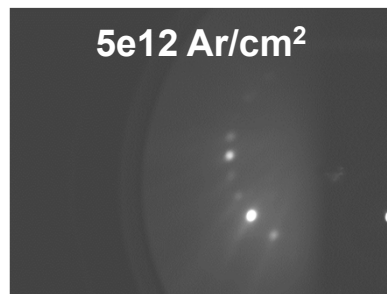
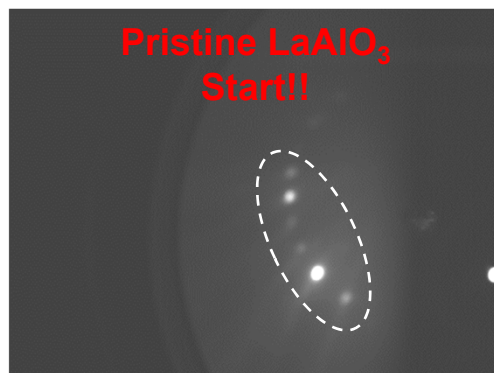


- Monte Carlo simulation show that the penetration depth is ~ 120 nm from the surface
- Calculated X-ray penetration depth is < 10 nm at a grazing angle of 0.25°
- After Ar irradiation, the LaAlO_3 single crystal phase near the surface is transformed into an amorphous phase

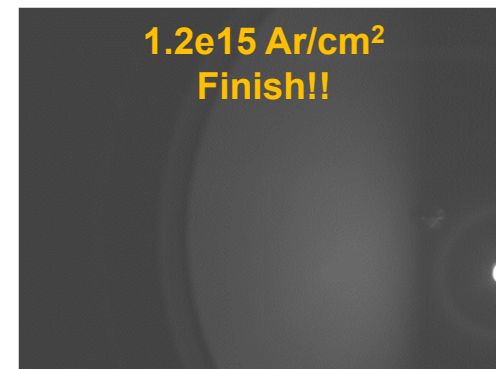
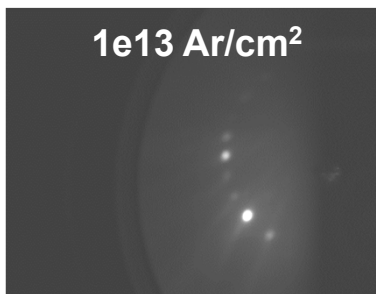
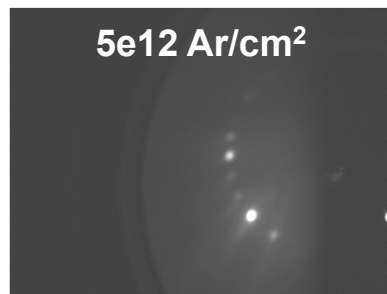
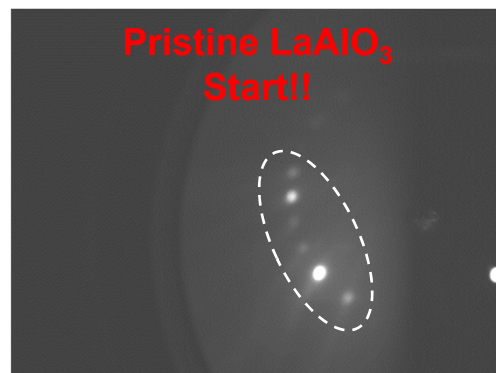
In-situ RHEED sequential images for 100keV Ar²⁺ions irradiation of c-LaAlO₃ at RT



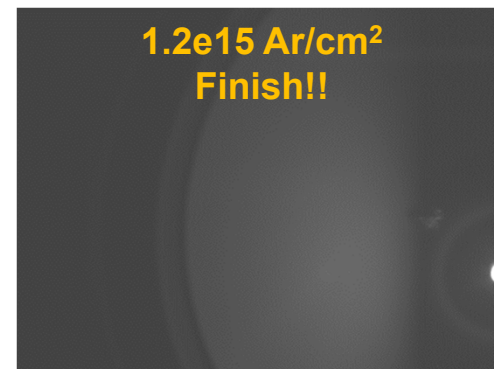
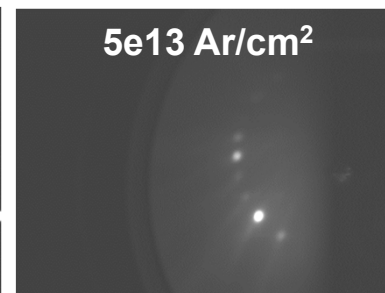
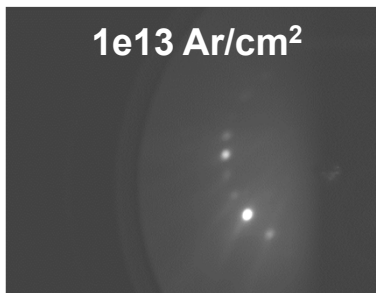
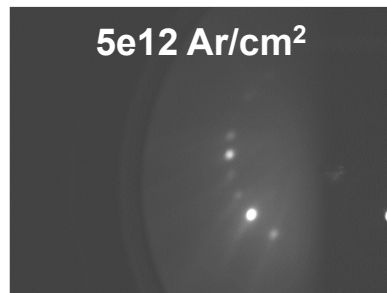
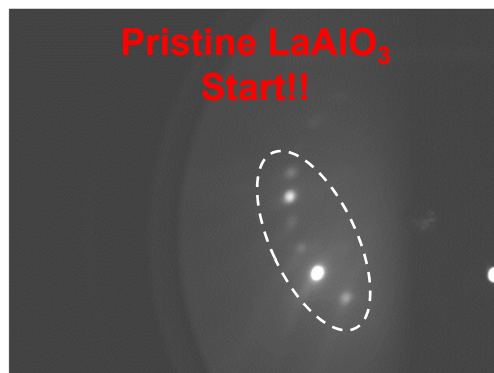
In-situ RHEED sequential images for 100keV Ar^{2+} ions irradiation of c- LaAlO_3 at RT



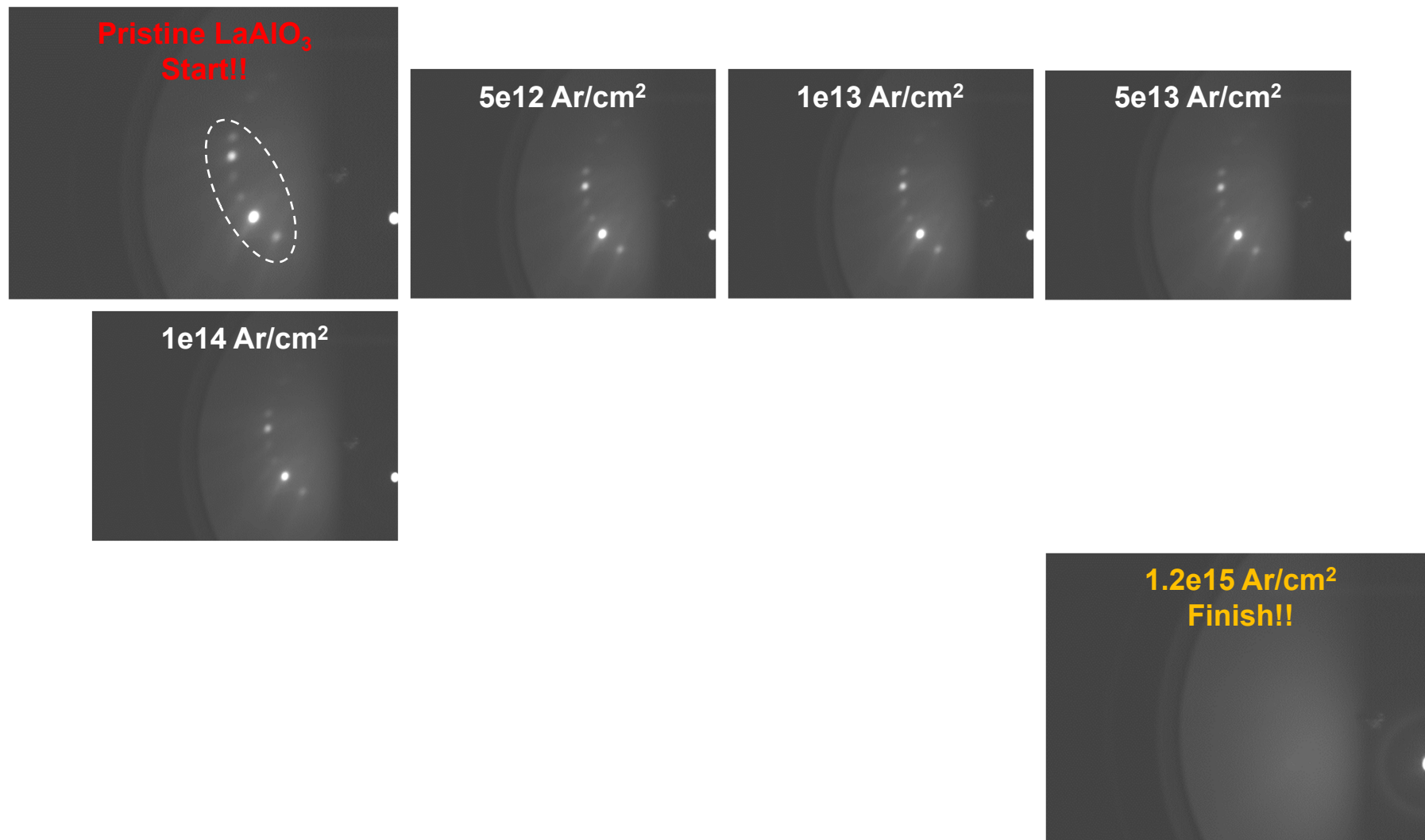
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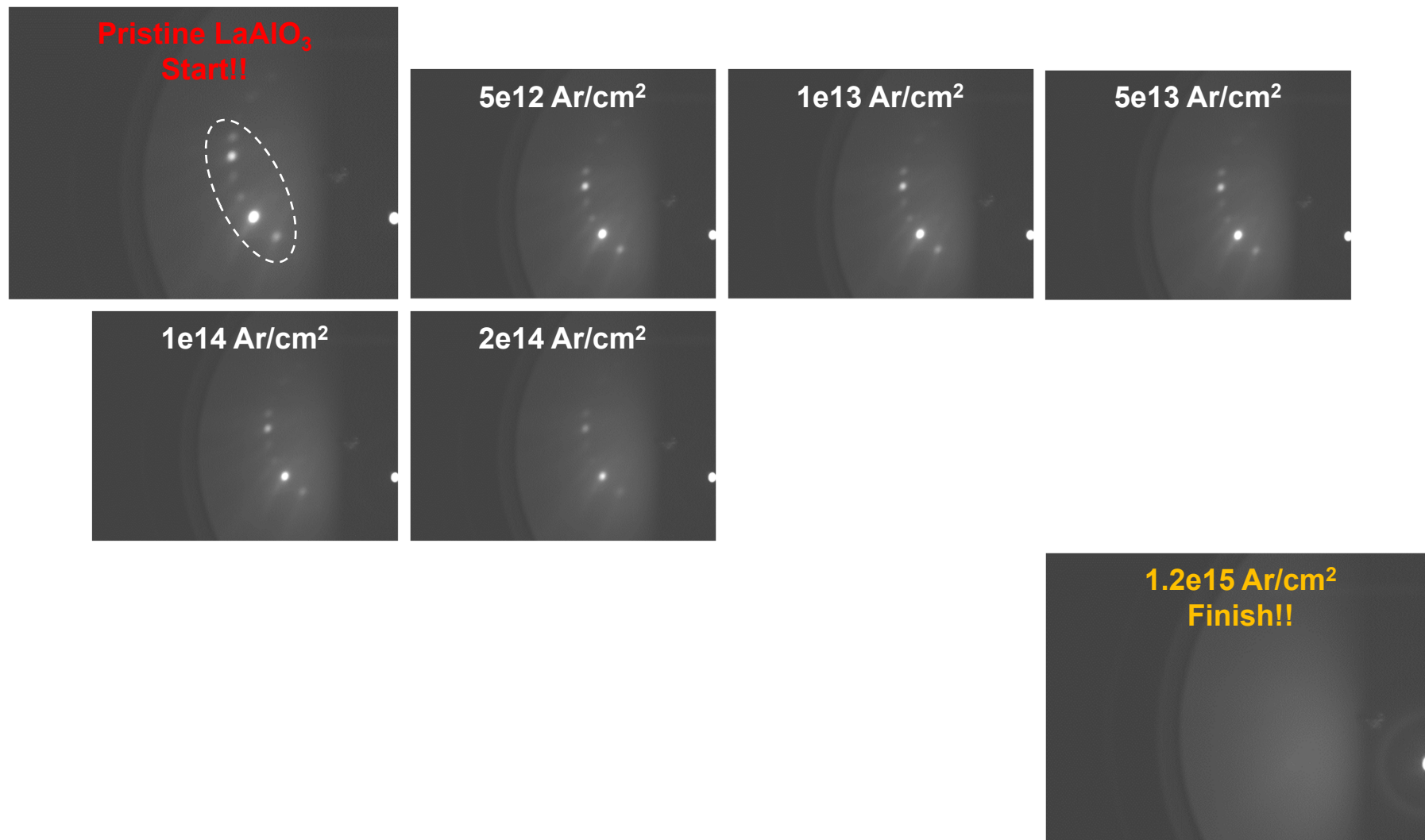
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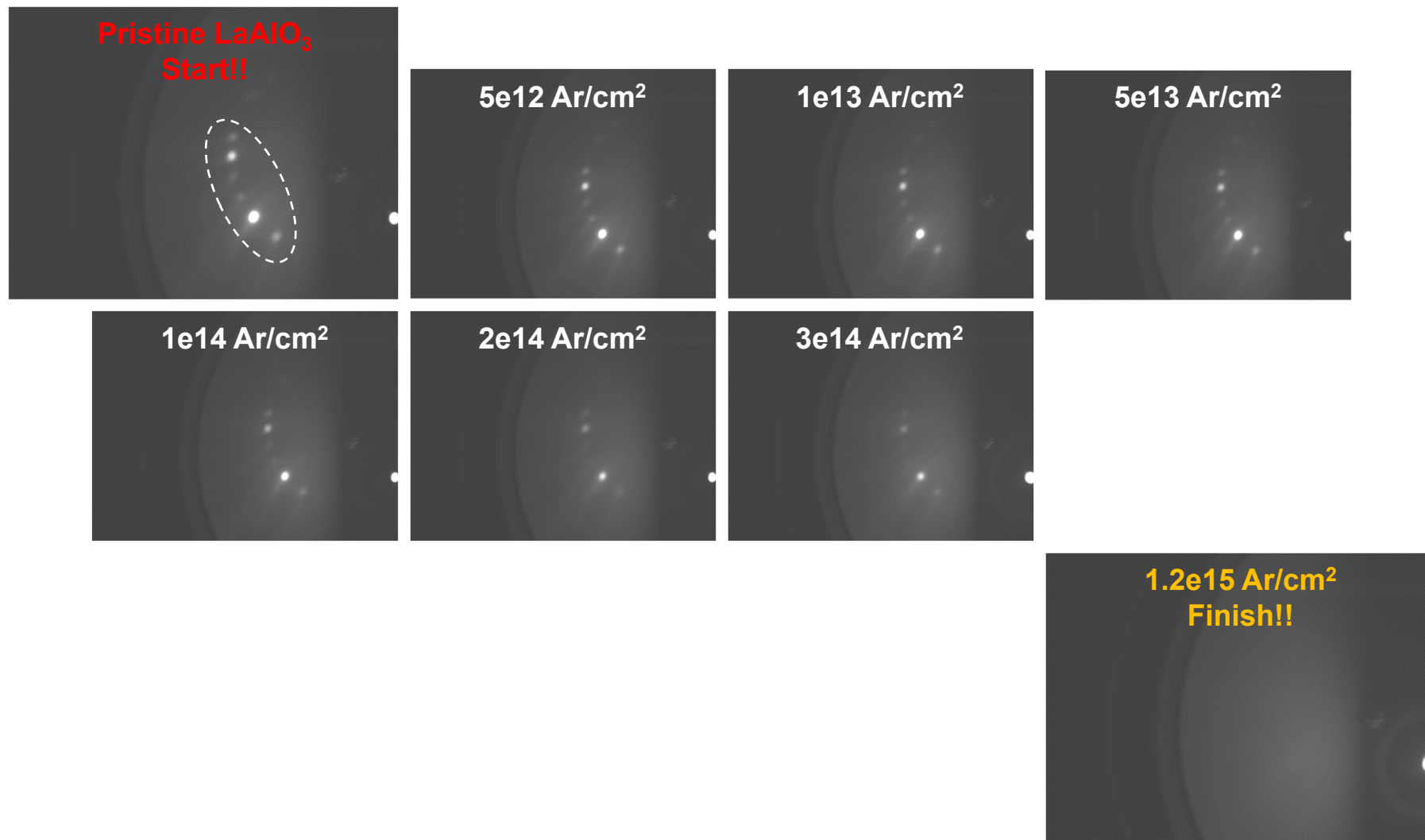
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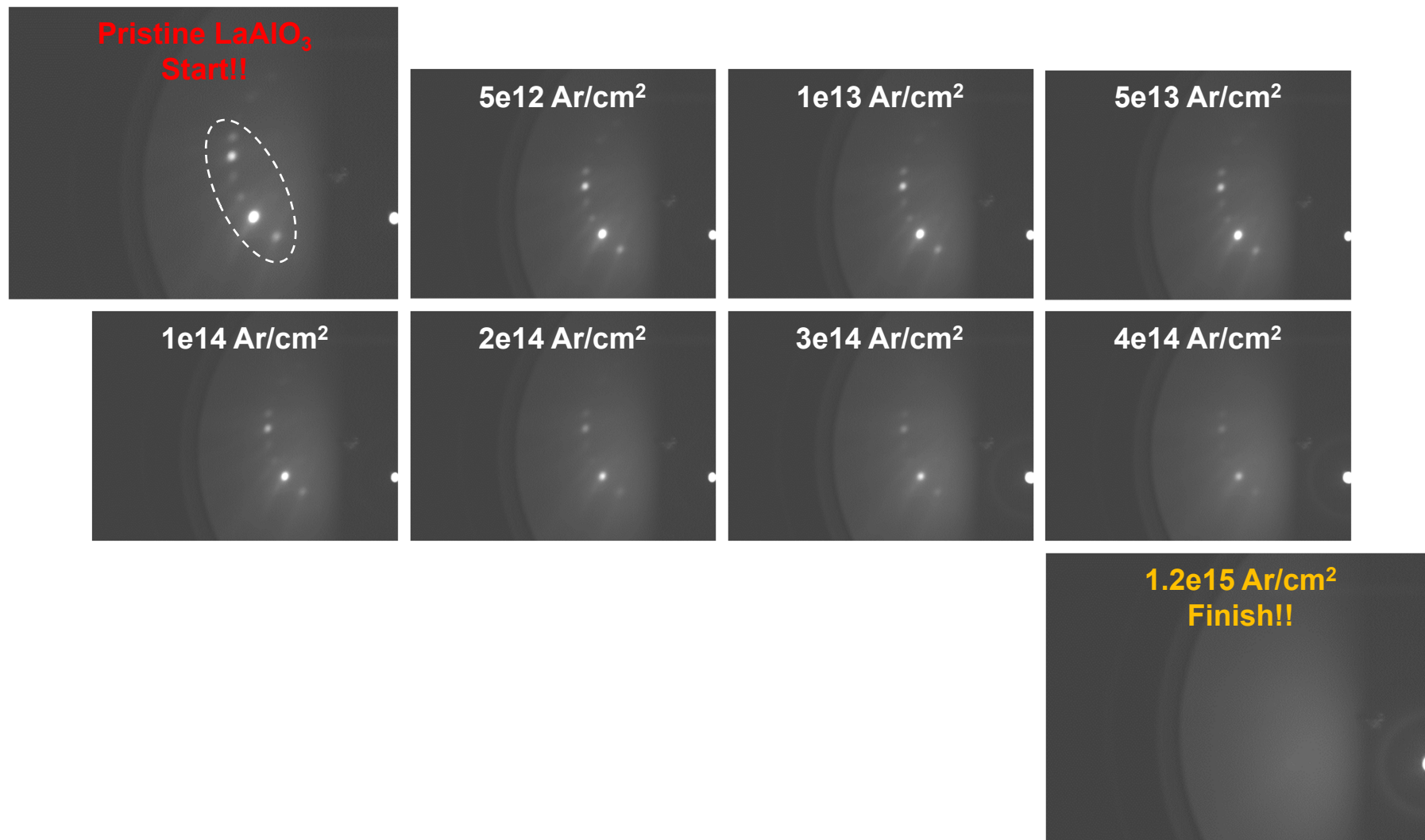
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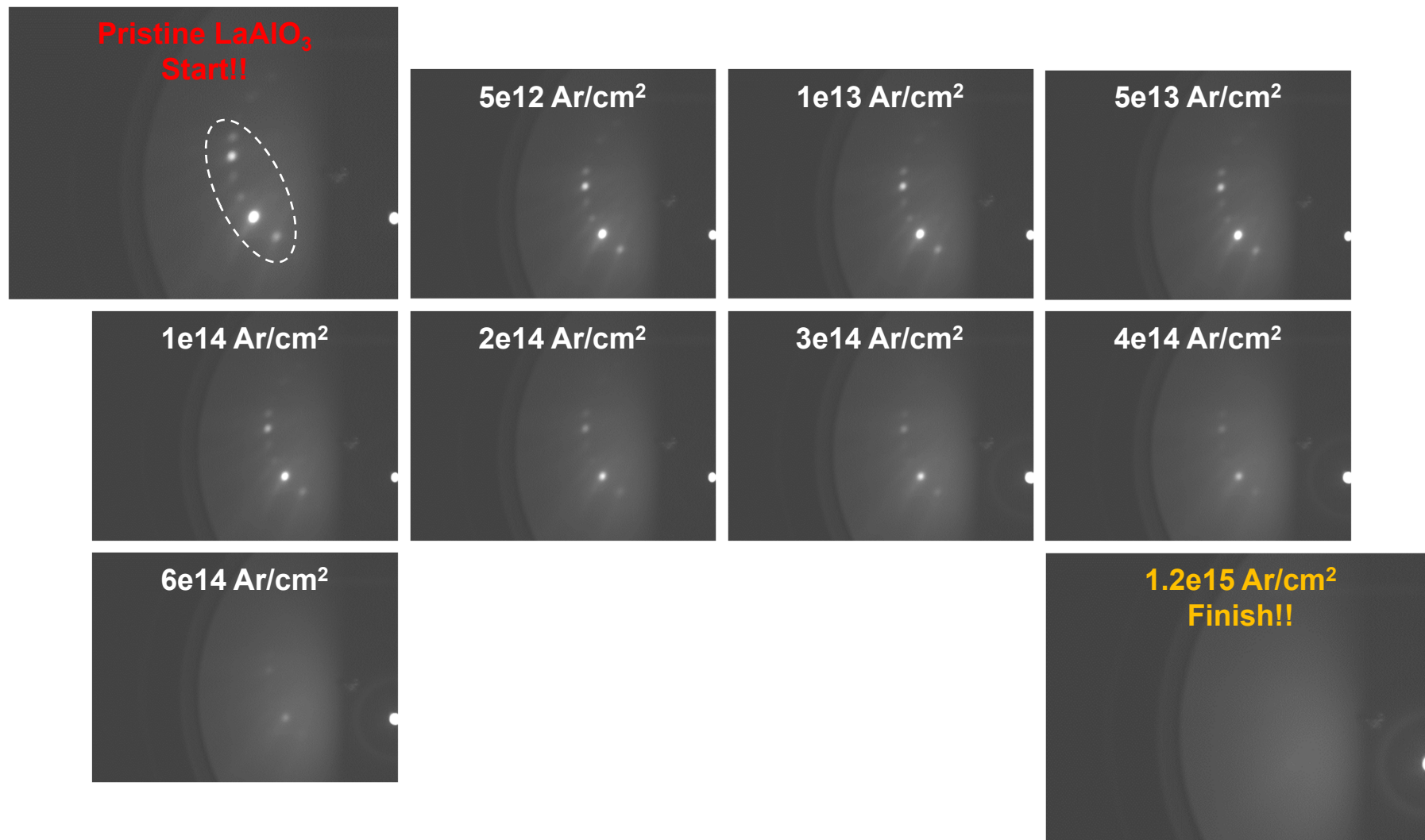
In-situ RHEED sequential images for 100keV Ar^{2+} ions irradiation of c- LaAlO_3 at RT



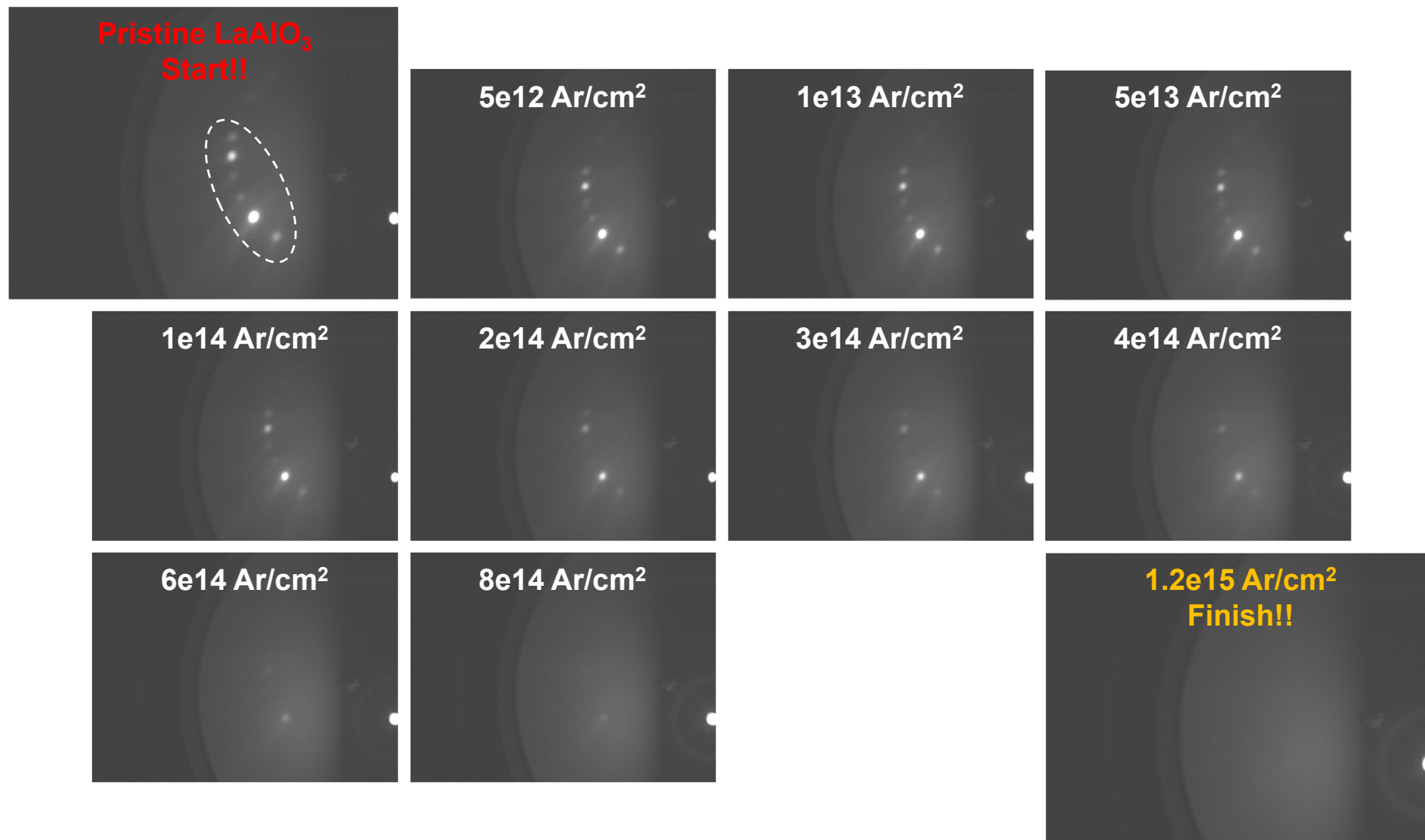
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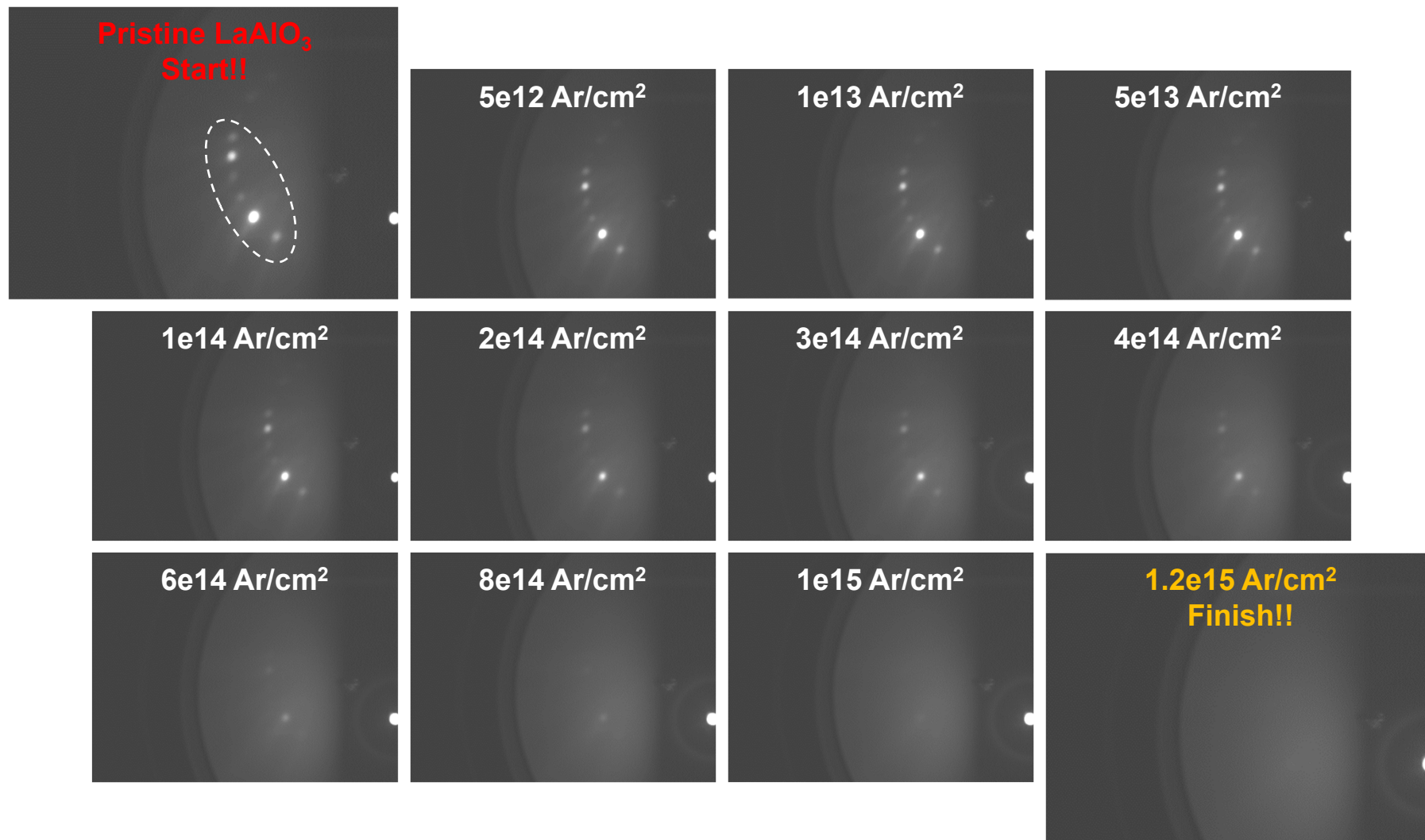
In-situ RHEED sequential images for 100keV Ar^{2+} ions irradiation of c- LaAlO_3 at RT



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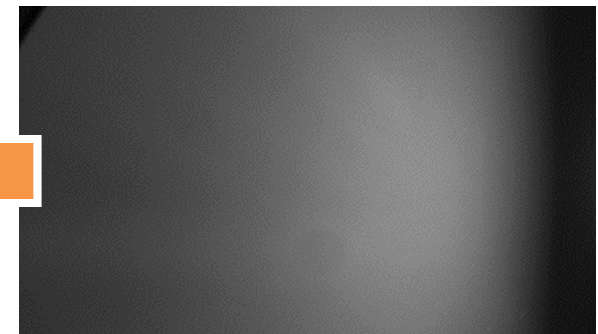
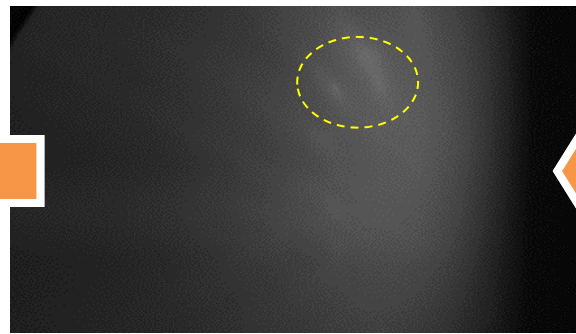
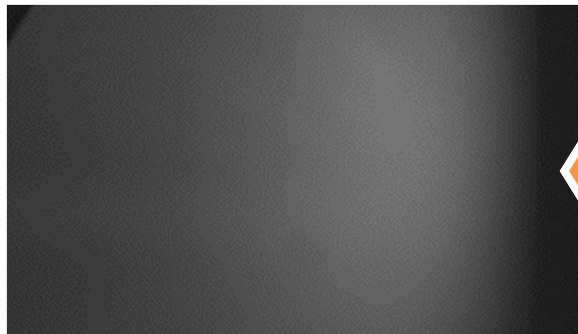
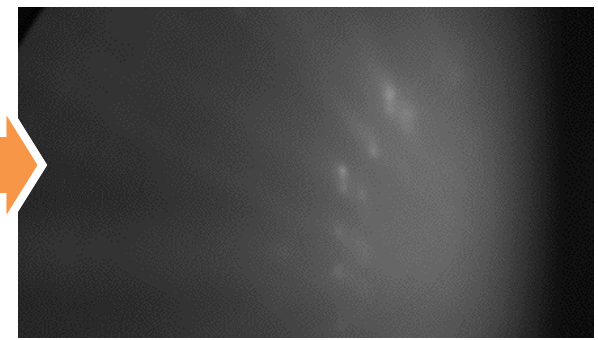
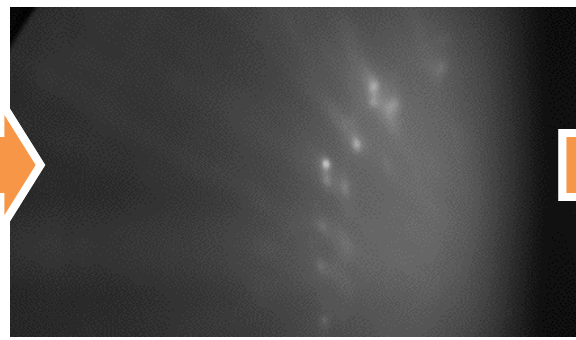
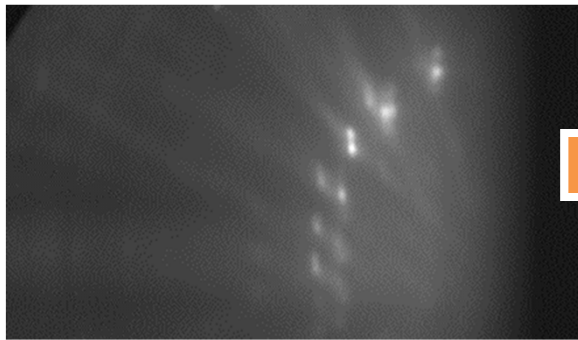


Readjusted e⁻ beam incident angle probe

Pristine- LaAlO₃

5e13 Ar/cm²

2.38e14 Ar/cm²

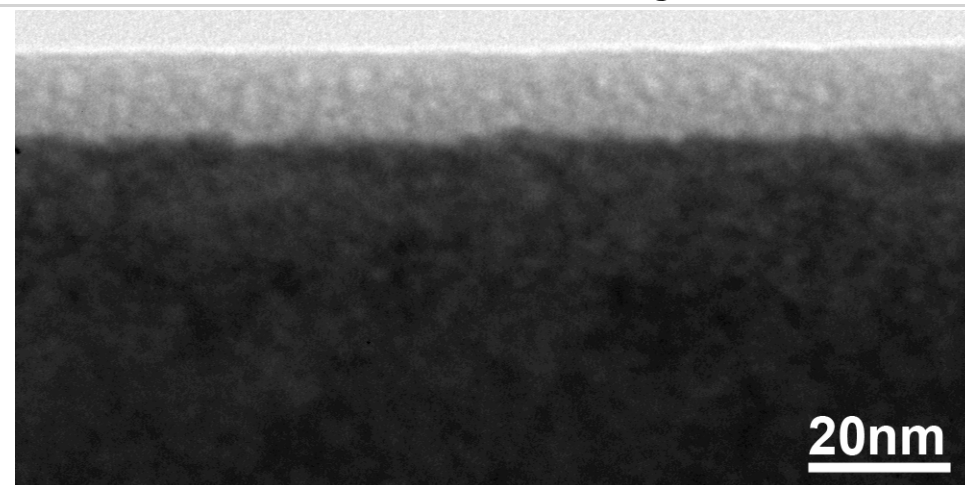


6.5e14 Ar/cm²

**Readjusted e⁻ incidence
angle probe deeper
into sample 3.5e14 Ar/cm²**

3.5e14 Ar/cm²

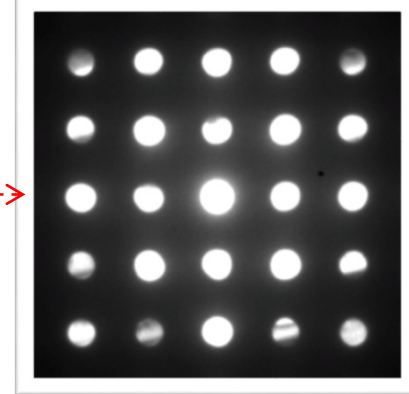
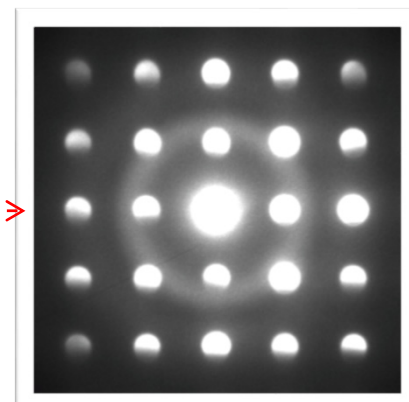
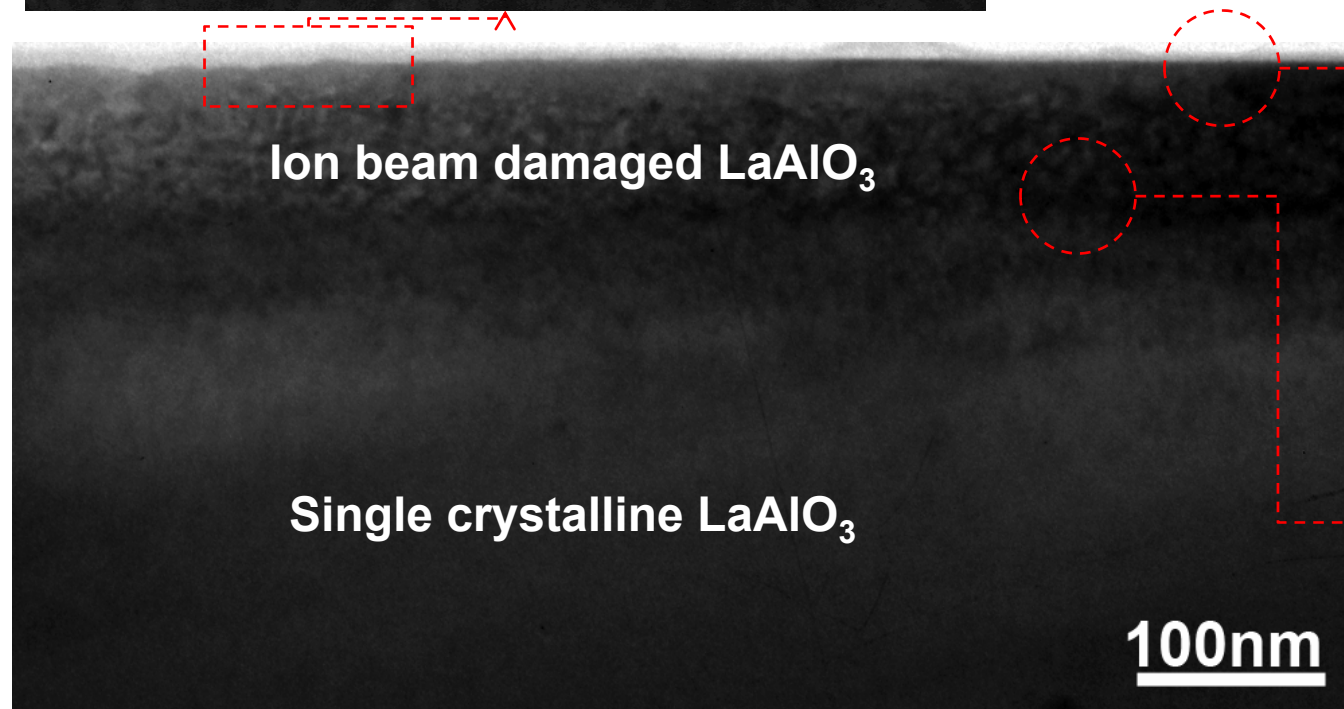
TEM and MBD analysis of 100keV Ar²⁺ ions irradiated sc-LaAlO₃ at RT



~ 10 nm-thick amorphous
layer

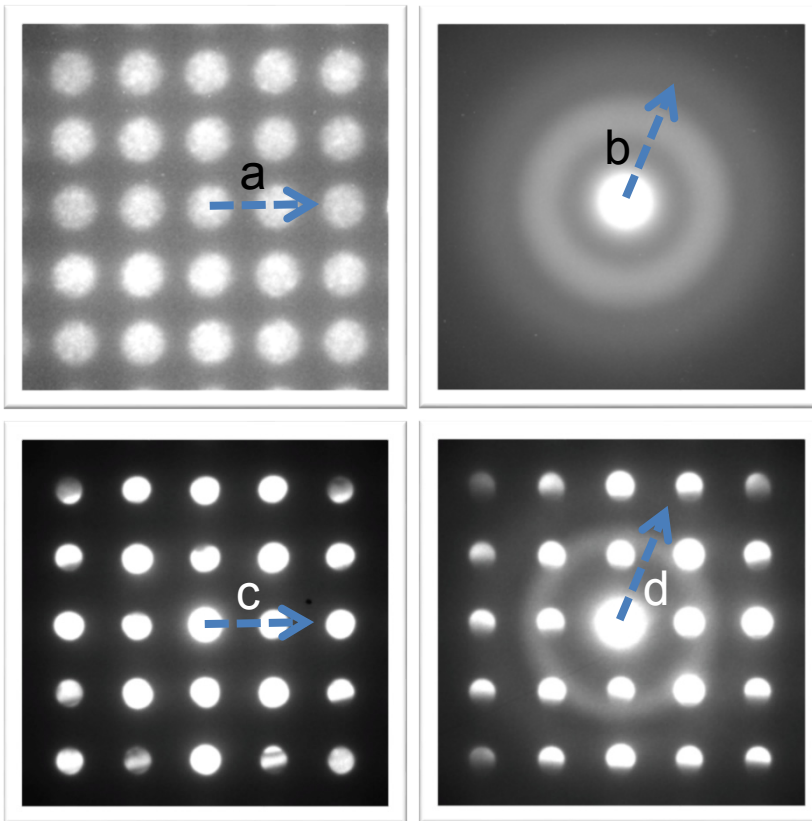


Damage layer



MDP analyses of ion beam induced a-LaAlO₃

400 kV Xe irradiation

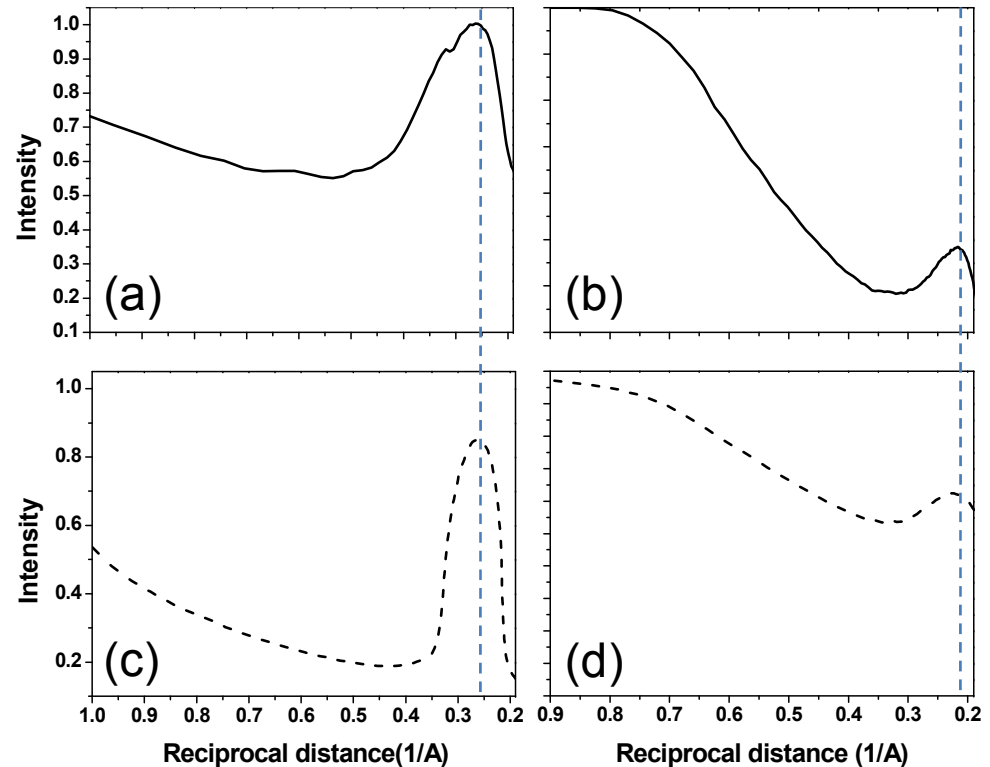


100keV Ar irradiation

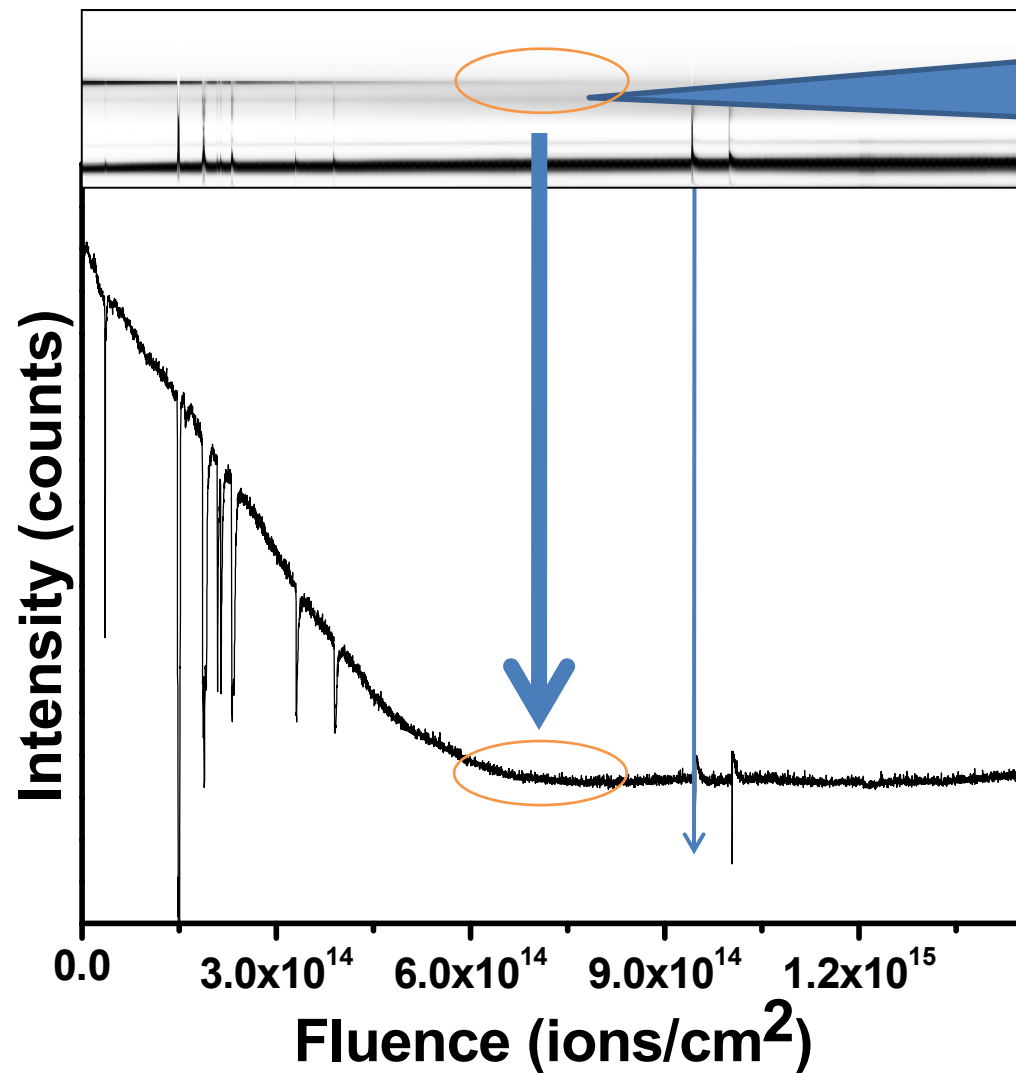
Calculated reciprocal lattice distances from Xe (upper) and Ar (lower) are identical
→ Crystalline (c) LaAlO₃ is transformed to an amorphous (a) phase by ion irradiation

Spot spacing

Hallo spacing



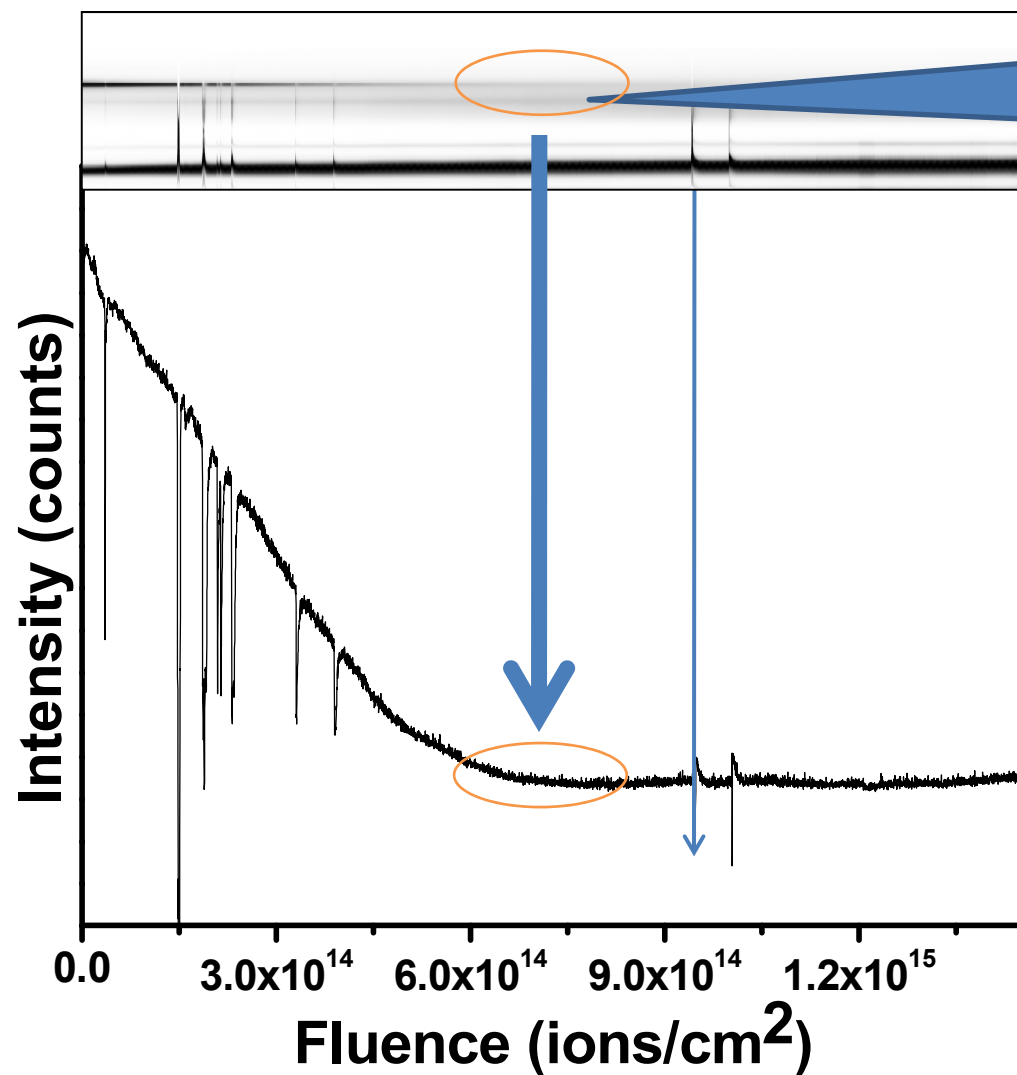
In-situ diffraction spot intensity evolution of LaAlO_3 at cryo temp.



Intensity of crystalline diffraction spot completely disappeared around $6\sim 8 \times 10^{14}$ ions/cm²

Intensity of diffraction spot is decreasing with irradiation time, and finally, the spot completely disappeared

In-situ diffraction spot intensity evolution of LaAlO_3 at cryo temp.

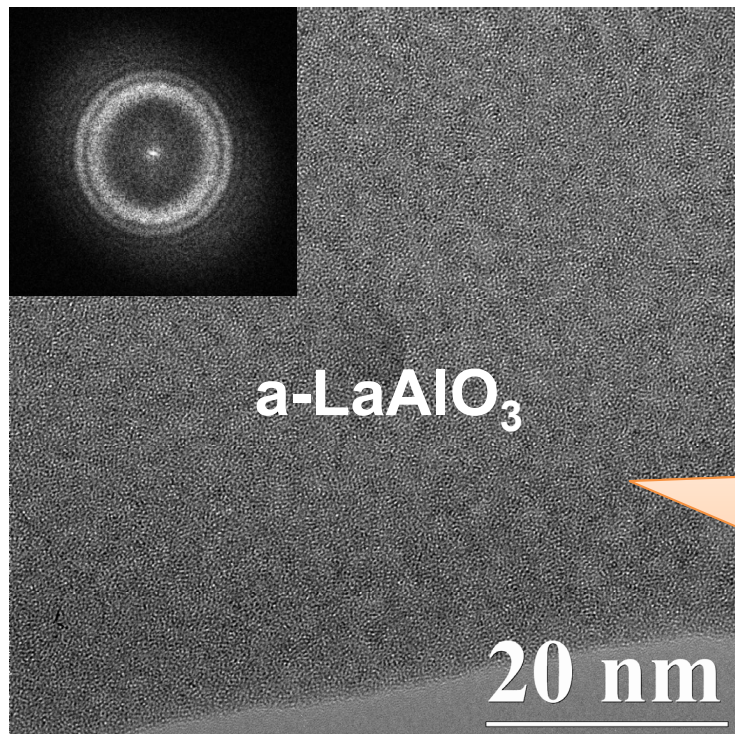
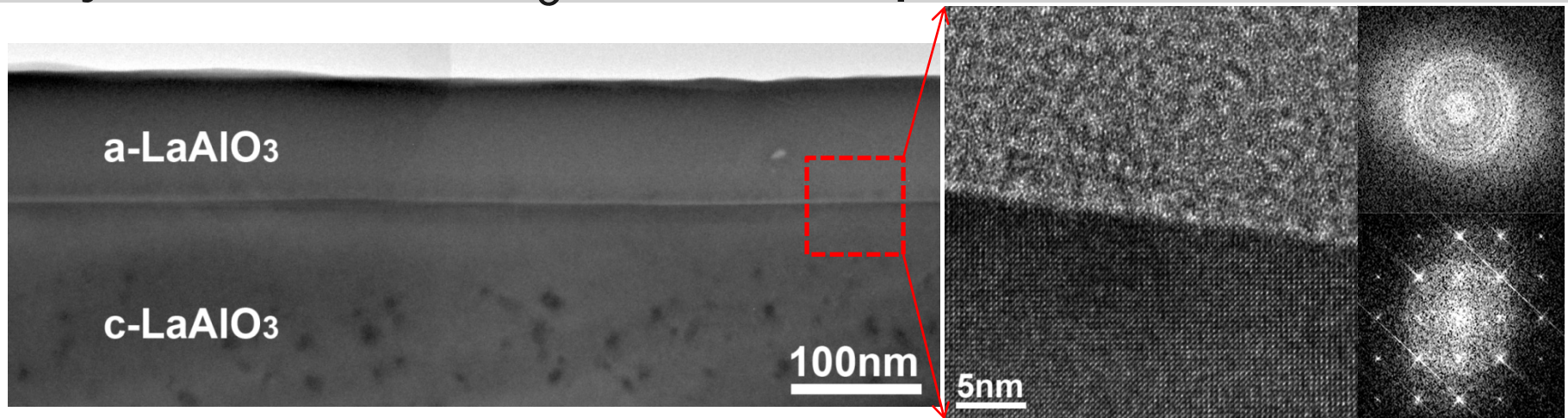


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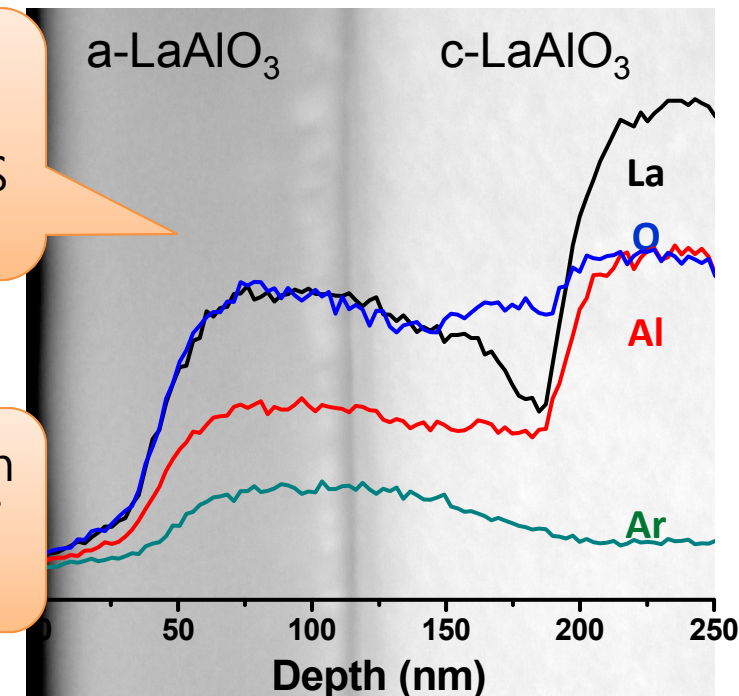
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TEM/STEM-EDS observations for crystalline LaAlO_3 at low temp.



HAADF image with STEM-EDS

High resolution TEM image of a-LaAlO_3



1. Crystalline-to-amorphous (c-a) phase transformation of LaAlO_3 was investigated by **combining 100 keV Ar^{++} ion irradiation with in-situ RHEED system.**
 - **RT:** around 100 nm-thick amorphous layer formed by irradiation
 - **Cryogenic temp.:** more than 100 nm-thick amorphous layer was formed by irradiation ($\sim$ identical to damage depth from SRIM2009 calculation)
2. Measured c-to-a phase transformation time (fluence) is dependent on the incident angle of the electron-beam. In the case of an incident angle of 3° at cryogenic temp., in-situ RHEED observations show that the phase transformation fluence is around **$6\sim 8 \times 10^{14}$ ions/cm²**

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Thank You



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